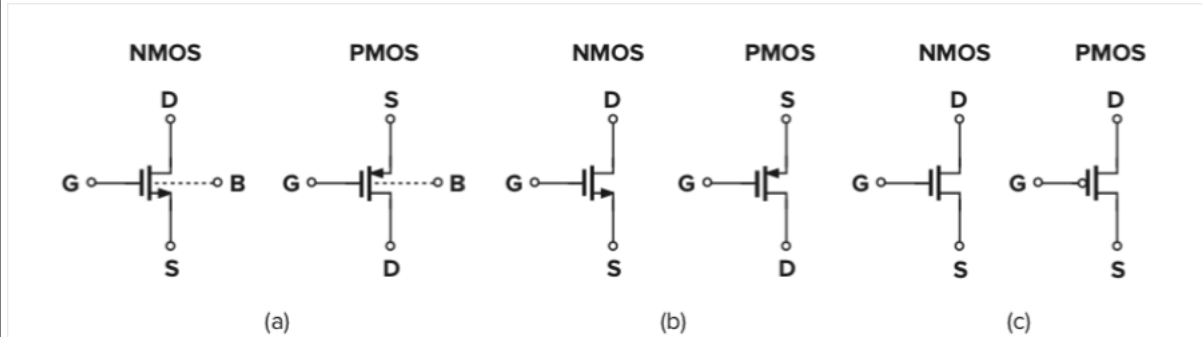
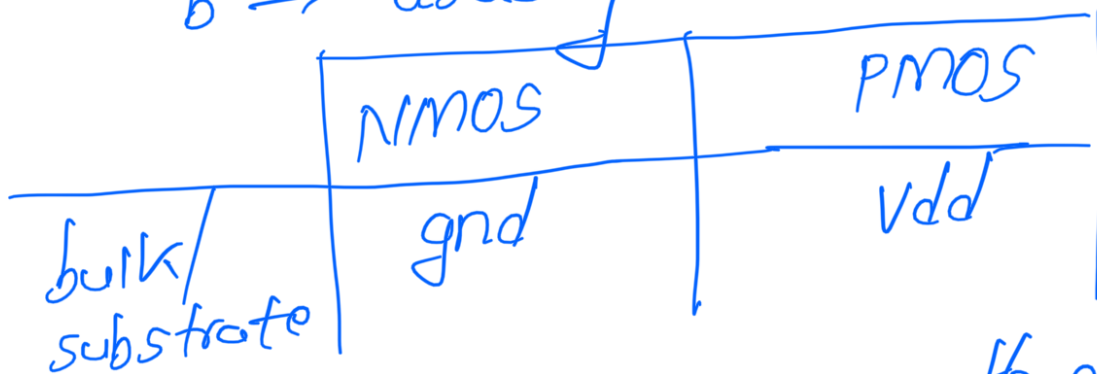


MOS Symbols :



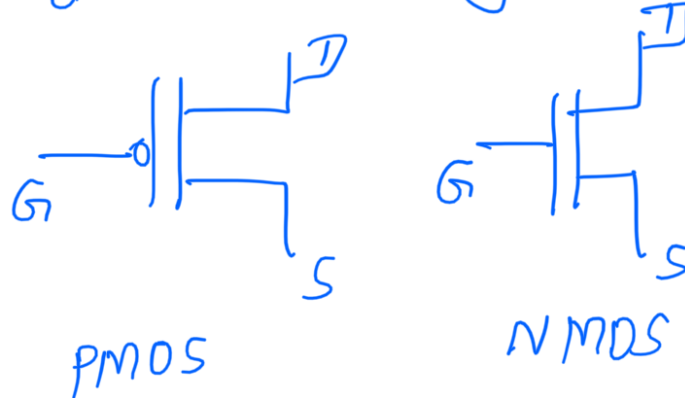
a \rightarrow typical structure

b \rightarrow usually we connect



So we are ignoring these terms representation.

c \rightarrow rep^d in digital circuits using a 'switch' symbols.



MOS I/V characteristics :-
generation & transport of charge
as a function of terminal voltage.

1. Threshold Voltage

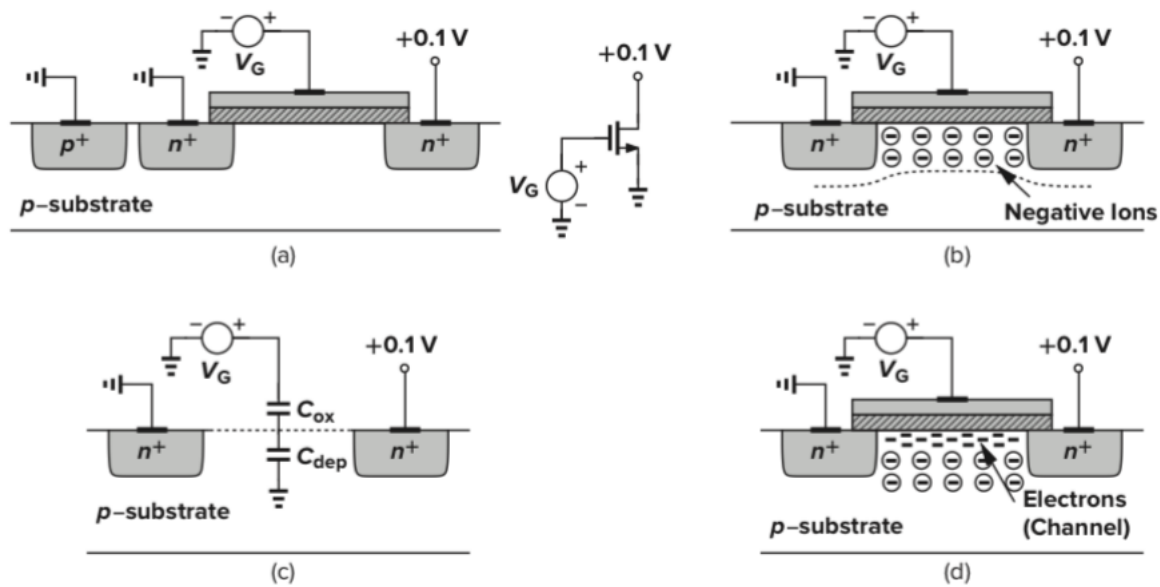
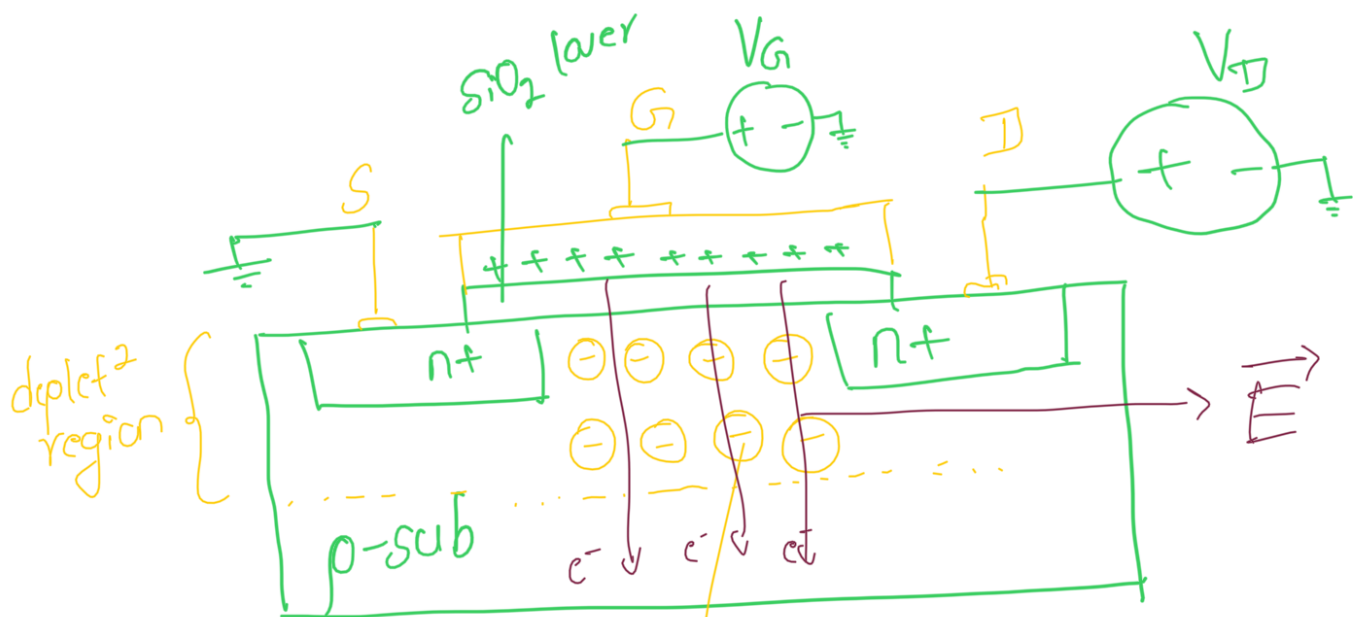


Figure 2.6 (a) A MOSFET driven by a gate voltage; (b) formation of depletion region; (c) onset of inversion; (d) formation of inversion layer.

When V_G increases from 0V,

- V_G becomes more $+^{ve}$
- holes in p -substrate repelled from gate area
 $\therefore +^{ve}$ repels $+^{ve}$

leaving $-^{ve}$ ions



negative ions
(immobile)

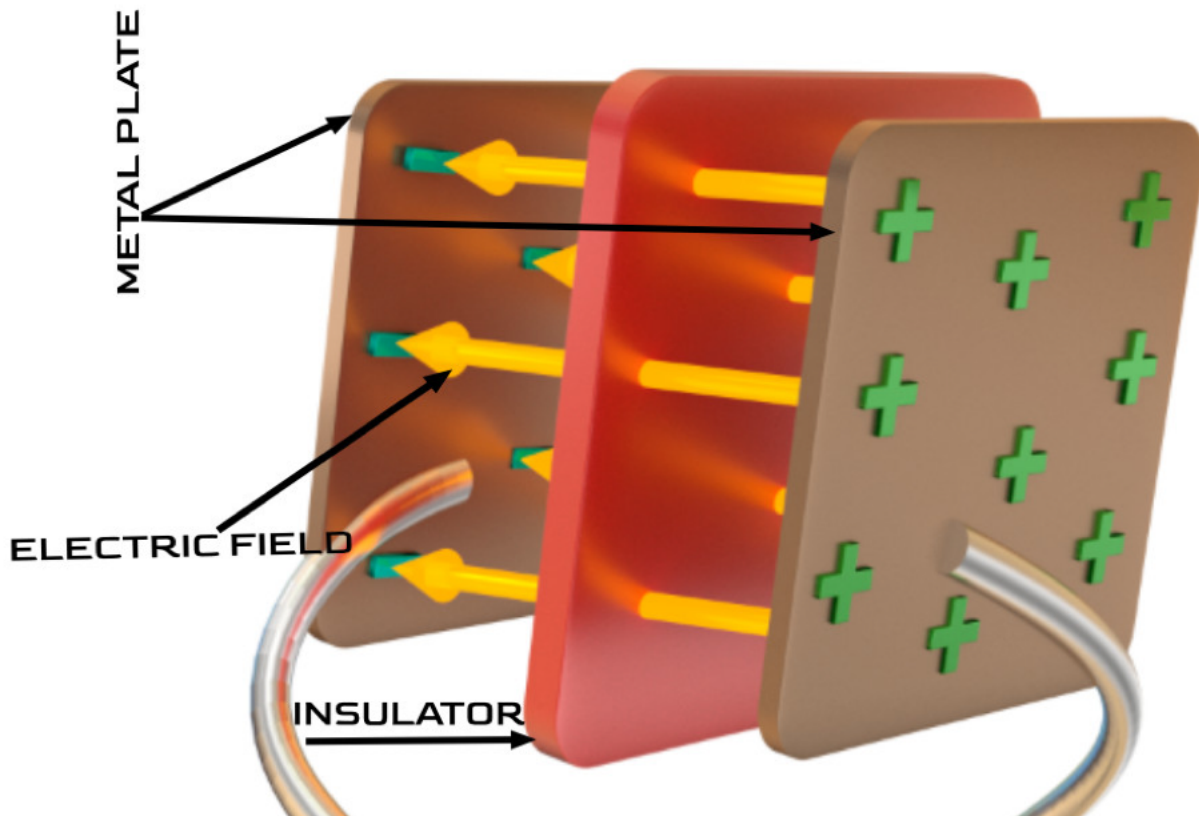
So no current conduction.

It resembles like 2 capacitors in

series :

oxide cap — C_{ox}
deple² region cap — C_{dep}

• When $V_G \uparrow$, interface potential \uparrow
So, at certain interface potential,
the electric field b/w



there are some free electrons even in the P-type region. The electric field produced by the capacitive action will attract the electrons

e^- flows from source to interface & eventually to drain.

° "channel" of charge carriers formed under gate oxide b/w S & D.

hey!! our transistor is now turned ON.

interface is inverted
channel = inversion layer

Threshold Voltage :- The value of V_G for which channel inversion occurs.
(V_{TH})

In Semiconductor Physics.

V_{TH} = gate voltage for which the interface is as much "n-type" as the substrate is p-type.

Substrate

$$V_{TH} = \phi_{ms} + 2\phi_F + \frac{Q_{dep}}{C_{ox}}$$

ϕ_{ms} → difference b/w work functions of polysilicon gate & silicon substrate.

$$\phi_F = \left(\frac{kT}{q} \right) \ln \left(\frac{N_{sub}}{n_i} \right)$$

k → Boltzman's constant
 $1.38 \times 10^{-23} \text{ J/K}$

q → electron charge
 $1.6 \times 10^{-19} \text{ Coulombs}$

N_{sub} → doping density of substrate

n_i → density of e^- in undoped Si

Q_{dep} → charge in depletion region

afmme

$C_{ox} \rightarrow$ gate-oxide capacitance
per unit area

$$t_{ox} \approx 20 \text{ \AA} \Rightarrow C_{ox} \approx 17.25 \text{ fF}/\mu\text{m}^2$$

But, in practice the native V_{TH} value may not be suited to circuit design.

V_{TH} is typically adjusted by implementation of dopants into channel area during device fabrication.

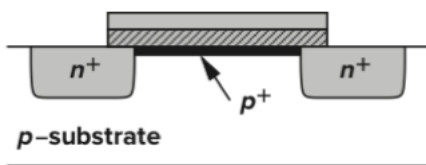


Figure 2.7 Implantation of $p+$ dopants to alter the threshold.

for PMOS, turn-ON phenomenon,
all polarities of NMOS reversed

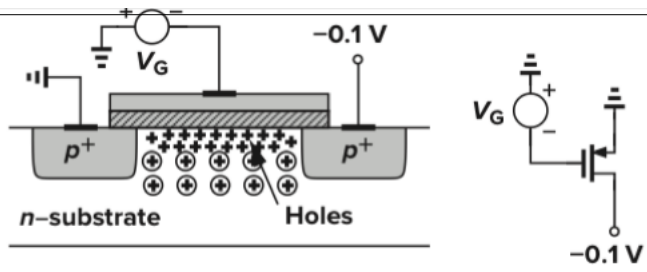


Figure 2.8 Formation of inversion layer in a PFET.